

Tabel 1

THIS IS A GUIDE LINE ONLY!

AR: Aspect Ratio

What are you looking for? Material	Roughness z<115nm	z>115nm	Step height z<115nm	z>115nm LowAR	z>115nm HighAR
Non transparent materials like Si and metals	Use Interferometry mode: PSI	Use Interferometry mode: CSI or ePSI	Use Interferometry PSI: gives you the best z resolution. Or use Confocal with high NA objective.	Use Confocal or Interferometry CSI/ePSI	Use Confocal or Interferometry CSI
Transparent materials like SiO ₂ , resists and polymers with thickness >	Use Interferometry mode: PSI	Use Interferometry mode: CSI or ePSI	Use Interferometry PSI: gives you the best z resolution.	Use Interferometry CSI or ePSI. Confocal may give the wrong values.	Use Interferometry CSI or ePSI. Confocal may give the wrong values.
Transparent materials like SiO ₂ , resists and polymers with thickness < aprox. 2µm	Use Interferometry mode: PSI	Probably not possible	Maybe possible if you deposit 10-20nm of nontransparent material on top (e.g. Al or Au). Try with Interferometry PSI mode.	Maybe possible if you deposit 10-20nm of nontransparent material on top (e.g. Al og Au). Try with CSI, ePSI or confocal.	Maybe possible if you deposit 10-20nm of nontransparent material on top (e.g. Al og Au). Try with CSI, ePSI or confocal.

